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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

RESPONSE UNDER CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1764

AF
1764/C
5/21/03
RA
10/3/03

In re application of

Yoichi MORI et al.

Serial No. 09/714,220

Filed November 17, 2000

ATTN: AF

Docket No. 2000-1578A

Group Art Unit 1764

Examiner H. T. TRAN

Correspondence

BOX

my 5/28/04

OK to Enter

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METHOD AND APPARATUS FOR TREATING A WASTE GAS CONTAINING
FLUORINE-CONTAINING COMPOUNDS

AMENDMENT AFTER FINAL

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Sir:

Responsive to the Final Office Action mailed February 21, 2003, please amend the
above-identified application as follows:

IN THE CLAIMS:

Please amend claims 9, 14 and 21 as follows:

9. (Amended) An apparatus for treating a waste gas containing fluorine-
containing components, comprising:

a solids treating device for separating solids from a waste gas containing fluorine-
containing components;

an addition device for adding to the waste gas leaving said solids treating device
one of

(i) H₂ and/or H₂O, and

(ii) H₂ and/or H₂O and O₂